



# Variable Capacitance and Pull-in Voltage Analysis of Electrically Actuated Meander-Suspended Superconducting MEMS

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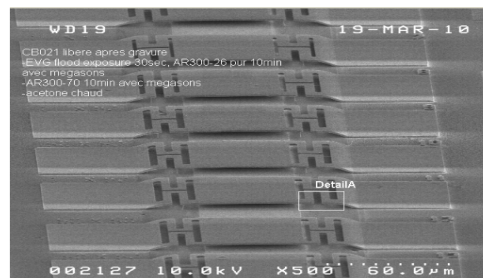
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## Context

- Use of superconducting MEMS for tuneable RF devices
- Behavioral multi physic model of a MEMS:
  - IRAM process : Niobium on quartz
  - Influence of the sacrificial layer

**Electro-Mechanical**

**Thermics  
(superconducting)**



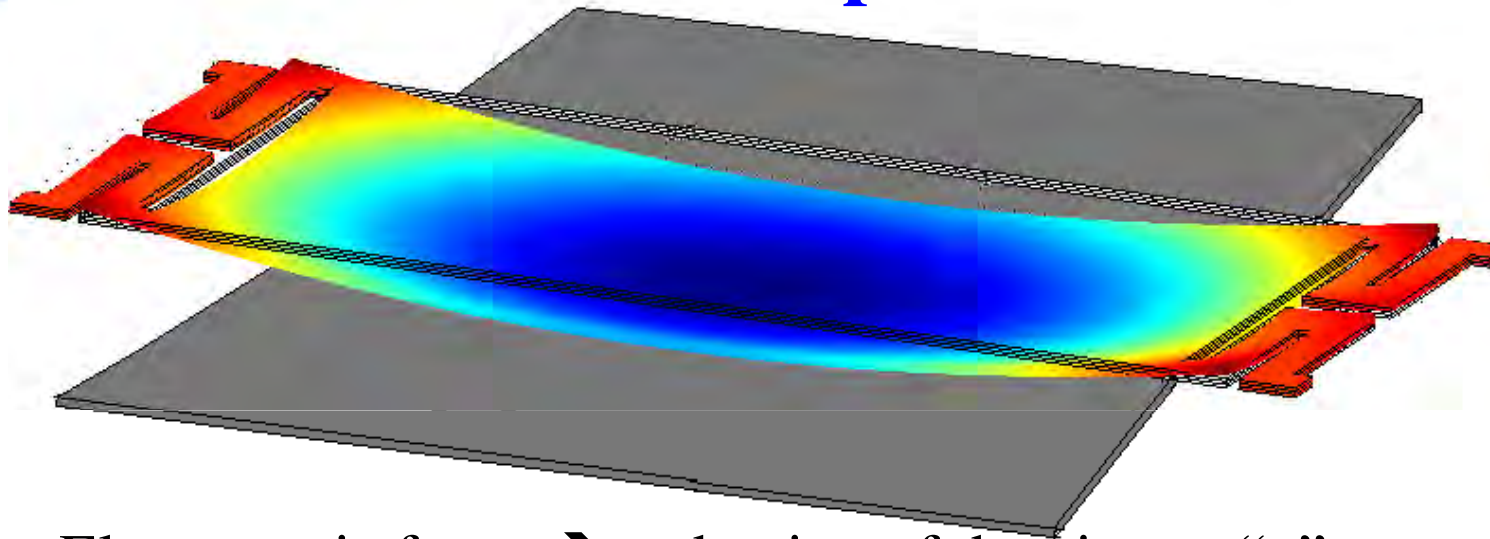
**Microwaves**



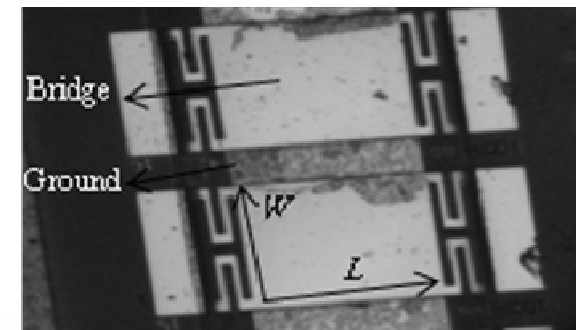
# Outline

- ❖ Presentation of suspended-meander MEMS
- ❖ Experimental characterization
- ❖ Multiphysics simulation
  - ❖ Mechanical simulation
  - ❖ Coupled Simulation without electrostatic force
  - ❖ Coupled Simulation with electrostatic force
- ❖ Conclusions & Perspectives

# Presentation of suspended-meander MEMS



- Electrostatic force → reduction of the air gap “g”
- Variation of the capacitance :  $C = \frac{\epsilon_0 \times b \times L}{g} \rightarrow \phi$
- Deformation of the meanders
- $C(V)$  depends on the meanders
- Optimal  $\Delta C/C$



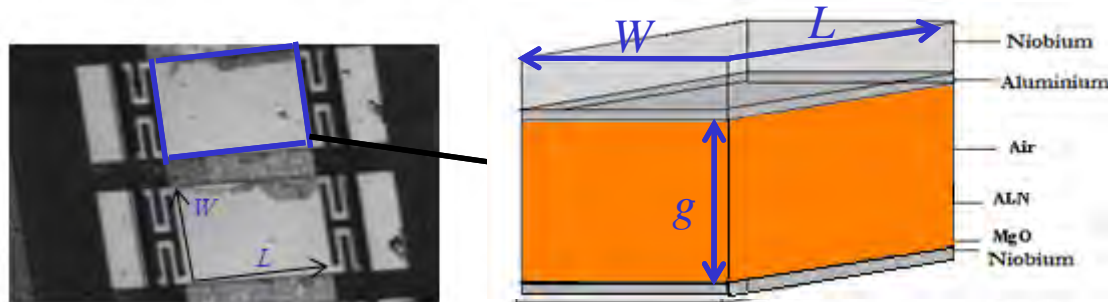


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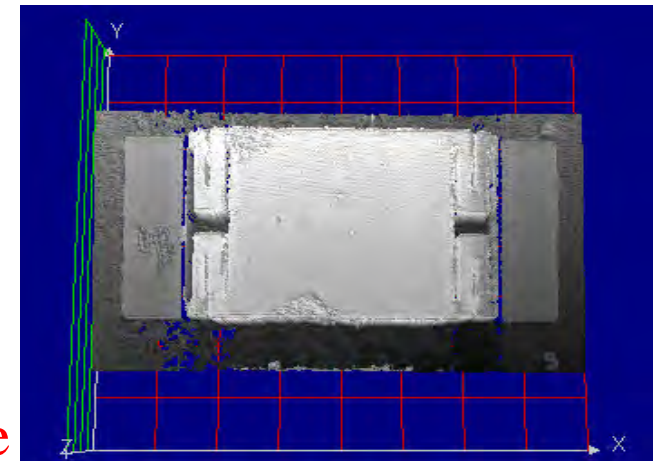
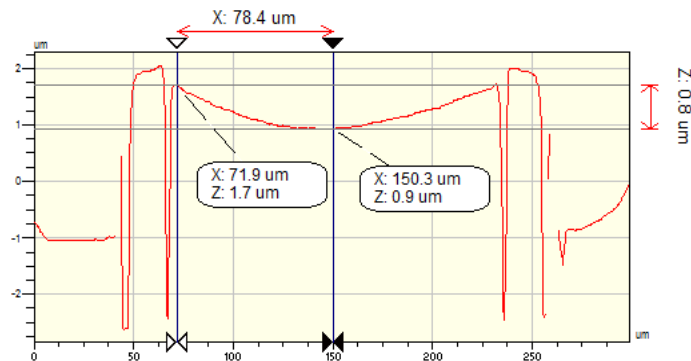
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# Experimental characterization

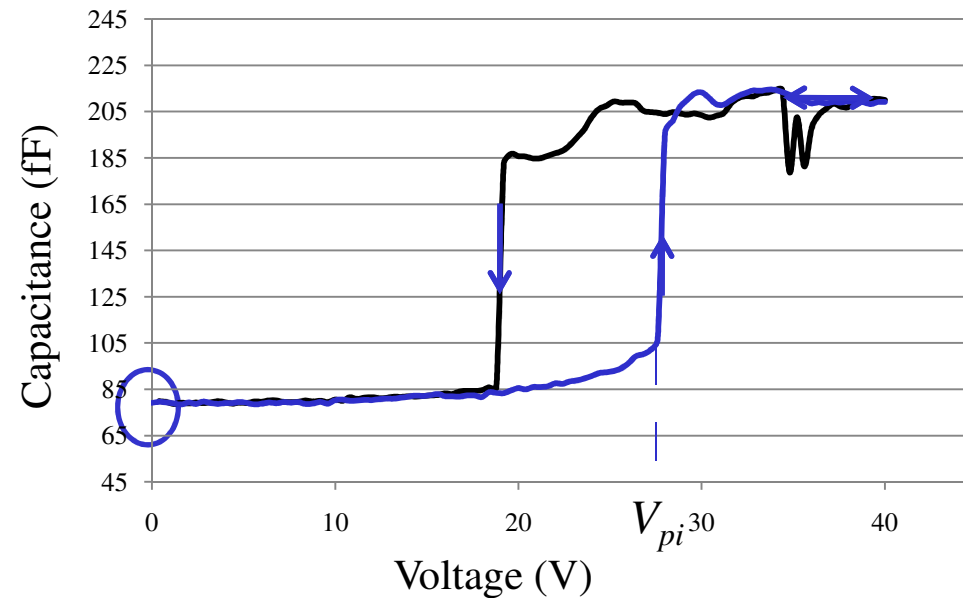
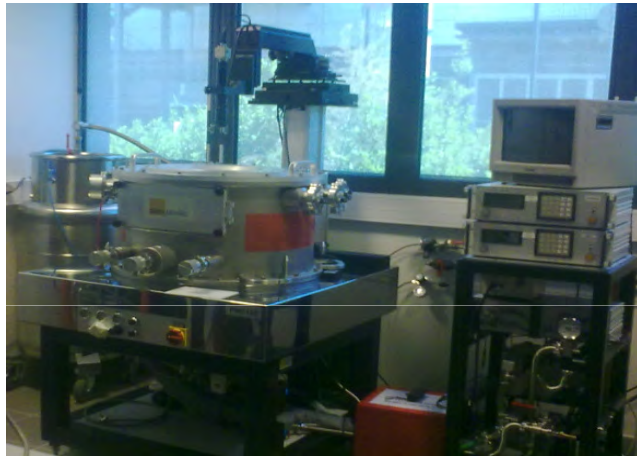


- $L=160\mu\text{m}$ ,  $W=100\mu\text{m}$ ,  $g=2.6\mu\text{m}$   
X Profile



- Q1 : Interferometric measurements shows that the MEMS bridge is initially slightly deflected.

# Experimental characterization



$V_{pi} = 27.6$  V and  $\Delta C(V)/C(0)$  is 33%.

**Q2 :  $C(0)_{measure} = 79\text{fF}$  &  $C(0)_{Calculated} = 67\text{fF}$**

Can COMSOL help us to answer these questions ?



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# COMSOL multiphysic simulation

## Objectives

- Mechanical simulation to explain the deflection of the bridge
- Coupled simulation to find extra capacitance origin.
- Multiphysics electromechanical simulation to describe  $C(V)$  measured for suspended –meanders MEMS

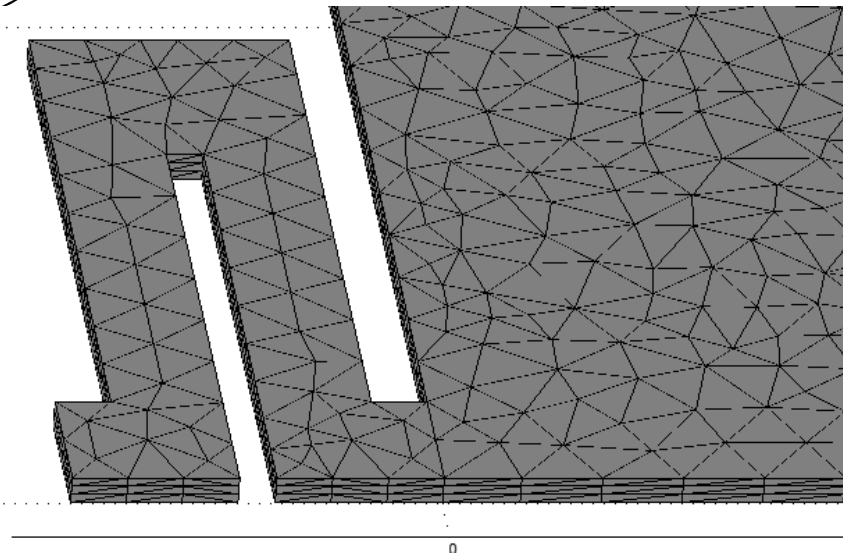
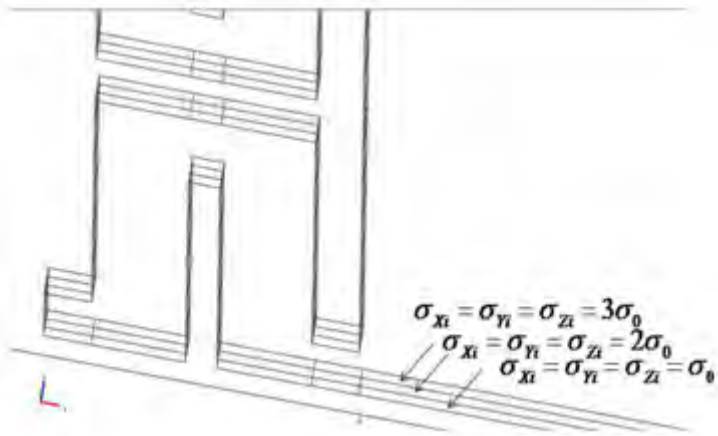
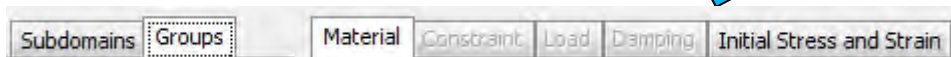
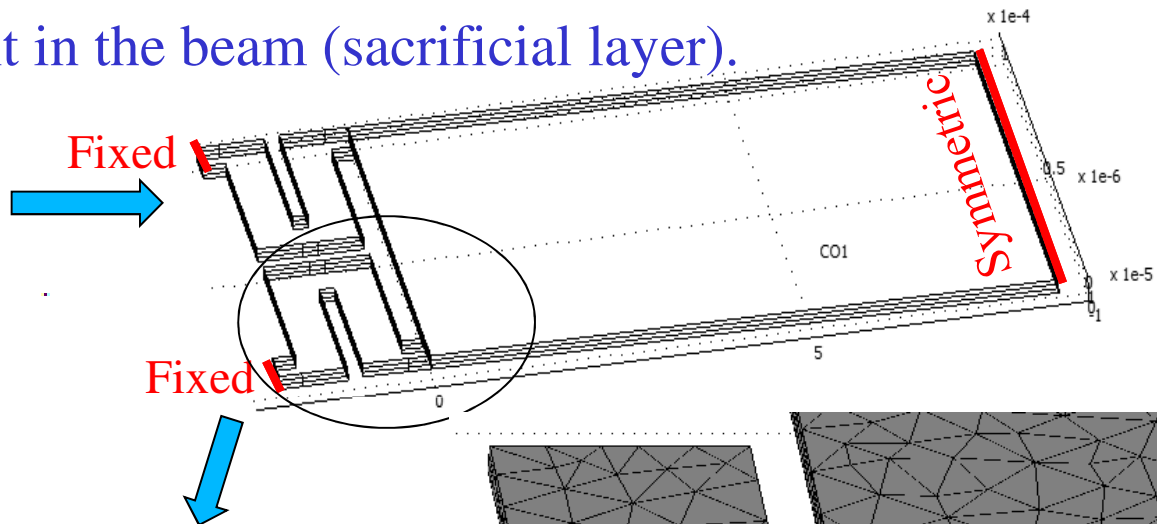
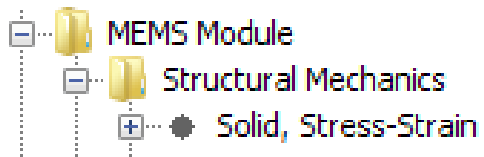


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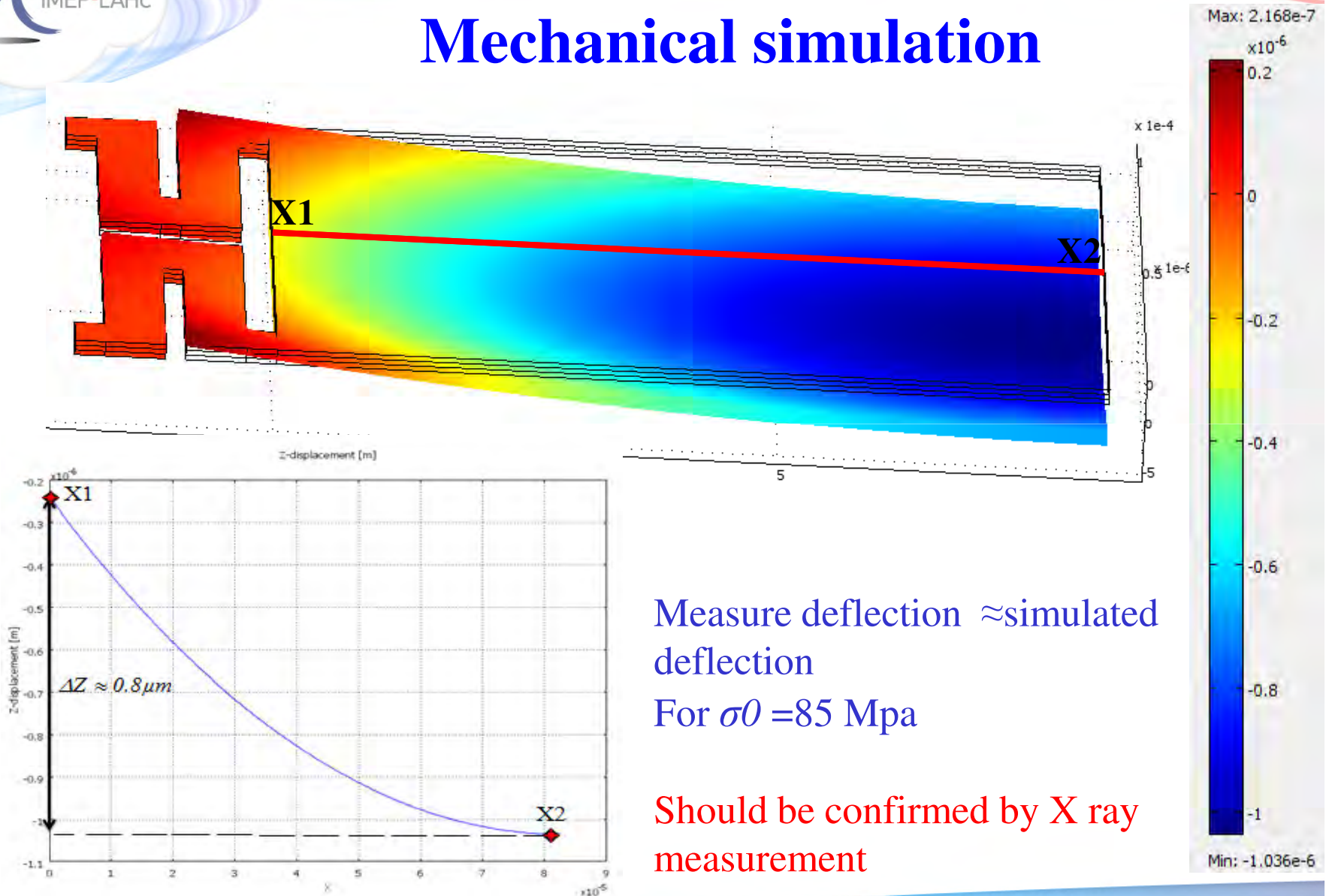
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# Mechanical simulation

- Assumption: Observed deflection result from intrinsic stress gradient in the beam (sacrificial layer).



# Mechanical simulation



Measure deflection  $\approx$  simulated deflection  
 For  $\sigma_0 = 85$  Mpa

Should be confirmed by X ray measurement

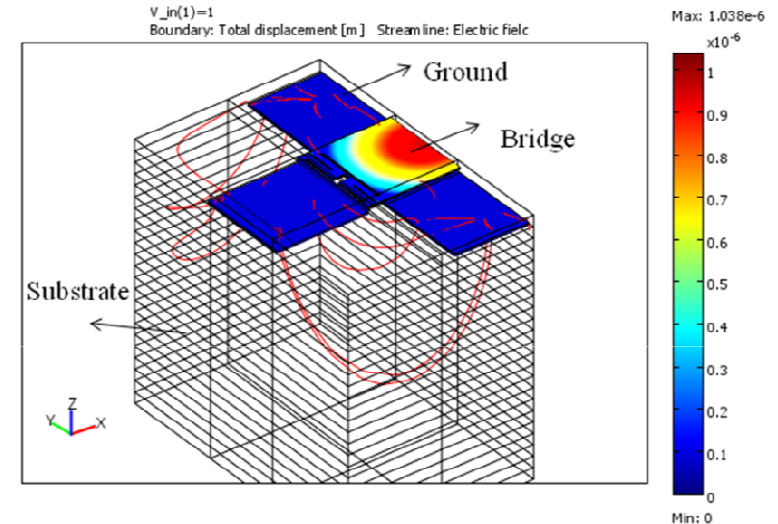
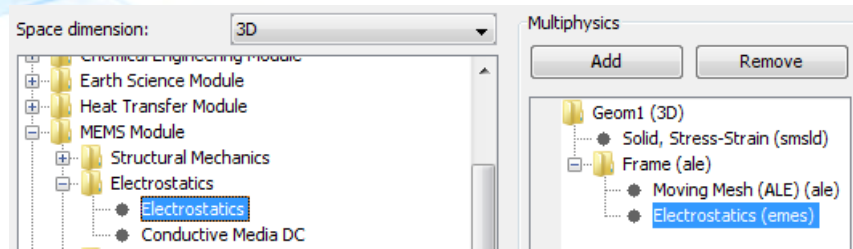


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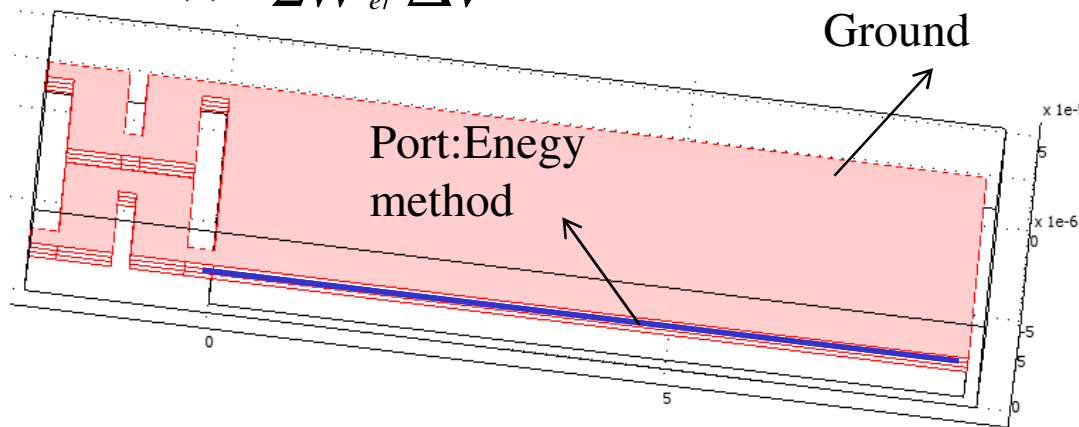


# Coupled simulation without electrostatic force



The value of the capacitance is

$$C(0) = 2W_e / \Delta V^2$$



$C(0) = 70 \text{ fF}$  with air substrate  
 $C(0) = 81.6 \text{ fF}$  with quartz

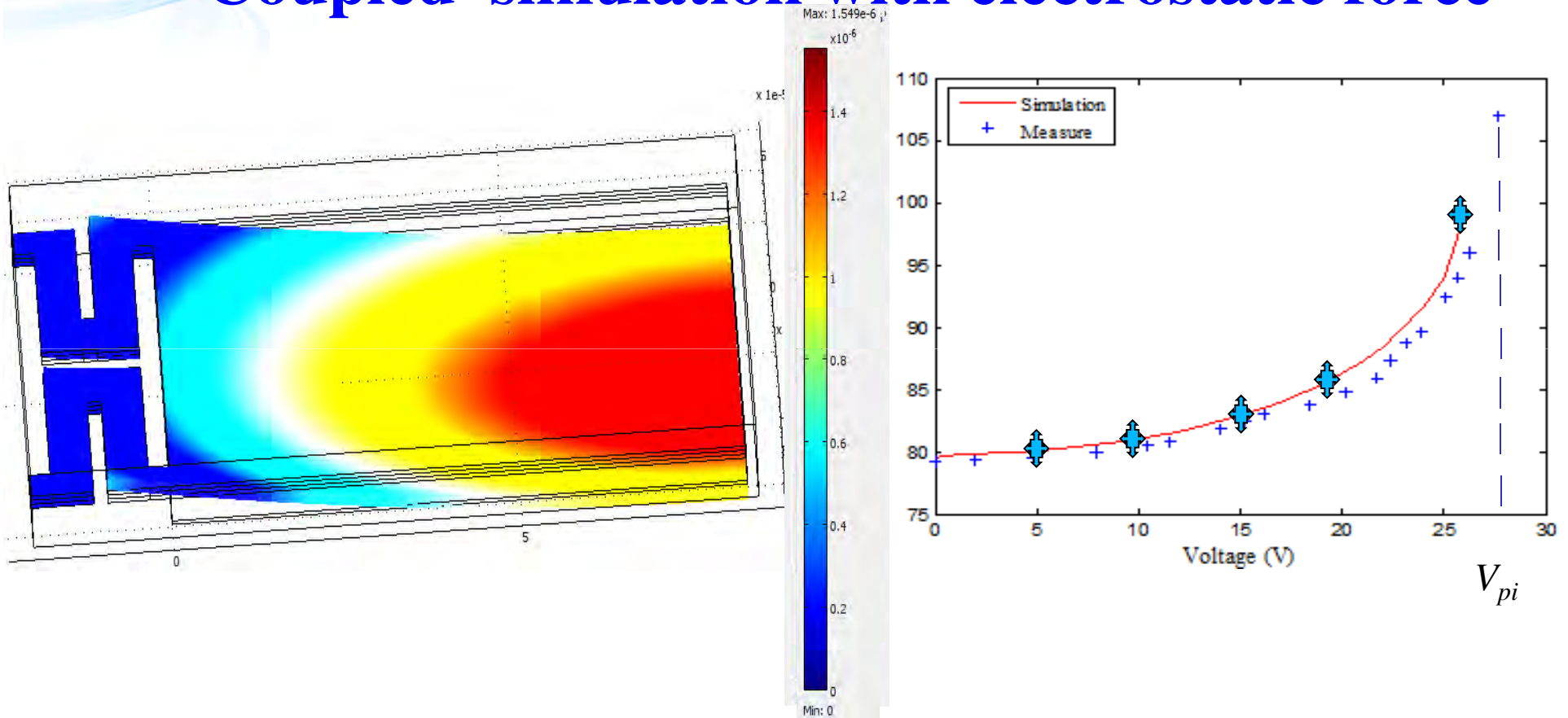
Extra capacitance : 11.6 fF as shown on measure



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# Coupled simulation with electrostatic force



$C(V)$  measure  $\approx C(V)$  simulation



## Conclusions & Perspectives

- C(V) is validated by an Electromechanical 3D simulation and predict the pull-in voltage
- The deflection of the bridges can be explained by an intrinsic stress gradient in the beam
- Extra capacitance is due to the quartz substrate
- Explain the effect of hysteresis by a simple simulation using COMSOL
- Superconducting modeling



**THANK YOU**

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